

Erwin Peiner

List of Publications by Year in descending order

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164
papers

2,731
citations

172443

29
h-index

254170

43
g-index

164
all docs

164
docs citations

164
times ranked

2117
citing authors

#	ARTICLE	IF	CITATIONS
1	Airborne engineered nanoparticle mass sensor based on a silicon resonant cantilever. <i>Sensors and Actuators B: Chemical</i> , 2013, 180, 77-89.	7.8	136
2	Doping Profile Analysis in Si by Electrochemical Capacitance-Voltage Measurements. <i>Journal of the Electrochemical Society</i> , 1995, 142, 576-580.	2.9	100
3	Piezoresistive cantilever as portable micro force calibration standard. <i>Journal of Micromechanics and Microengineering</i> , 2003, 13, S171-S177.	2.6	84
4	Thermoelectric Properties of High-Doped Silicon from Room Temperature to 900ÅK. <i>Journal of Electronic Materials</i> , 2013, 42, 2381-2387.	2.2	69
5	Silicon resonant nanopillar sensors for airborne titanium dioxide engineered nanoparticle mass detection. <i>Sensors and Actuators B: Chemical</i> , 2013, 189, 146-156.	7.8	63
6	Fabrication of ZnO nanorods and Chitosan@ZnO nanorods on MEMS piezoresistive self-actuating silicon microcantilever for humidity sensing. <i>Sensors and Actuators B: Chemical</i> , 2018, 273, 276-287.	7.8	62
7	Transport and optical properties of amorphous carbon and hydrogenated amorphous carbon films. <i>Applied Surface Science</i> , 2006, 252, 5387-5390.	6.1	61
8	Micro force sensor with piezoresistive amorphous carbon strain gauge. <i>Sensors and Actuators A: Physical</i> , 2006, 130-131, 75-82.	4.1	60
9	Sintering of Copper Particles for Die Attach. <i>IEEE Transactions on Components, Packaging and Manufacturing Technology</i> , 2012, 2, 1587-1591.	2.5	60
10	Piezoresistive microcantilevers for humidity sensing. <i>Journal of Micromechanics and Microengineering</i> , 2019, 29, 053003.	2.6	60
11	Handheld personal airborne nanoparticle detector based on microelectromechanical silicon resonant cantilever. <i>Microelectronic Engineering</i> , 2015, 145, 96-103.	2.4	59
12	GaN nanowire arrays with nonpolar sidewalls for vertically integrated field-effect transistors. <i>Nanotechnology</i> , 2017, 28, 095206.	2.6	58
13	Portable cantilever-based airborne nanoparticle detector. <i>Sensors and Actuators B: Chemical</i> , 2013, 187, 118-127.	7.8	50
14	Form measurement inside fuel injector nozzle spray holes. <i>Microelectronic Engineering</i> , 2009, 86, 984-986.	2.4	45
15	Diamond-like carbon for MEMS. <i>Journal of Micromechanics and Microengineering</i> , 2007, 17, S83-S90.	2.6	44
16	Capabilities of ICP-RIE cryogenic dry etching of silicon: review of exemplary microstructures. <i>Journal of Micromechanics and Microengineering</i> , 2009, 19, 105005.	2.6	44
17	A phase-locked loop frequency tracking system for portable microelectromechanical piezoresistive cantilever mass sensors. <i>Microsystem Technologies</i> , 2014, 20, 559-569.	2.0	44
18	Vertical GaN Nanowires and Nanoscale Light-Emitting-Diode Arrays for Lighting and Sensing Applications. <i>ACS Applied Nano Materials</i> , 2019, 2, 4133-4142.	5.0	44

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19	Pick-and-Place Silver Sintering Die Attach of Small-Area Chips. IEEE Transactions on Components, Packaging and Manufacturing Technology, 2012, 2, 199-207.	2.5	42
20	Femtogram aerosol nanoparticle mass sensing utilising vertical silicon nanowire resonators. Micro and Nano Letters, 2013, 8, 554-558.	1.3	38
21	Slender Tactile Sensor for Contour and Roughness Measurements Within Deep and Narrow Holes. IEEE Sensors Journal, 2008, 8, 1960-1967.	4.7	37
22	Versatilely tuned vertical silicon nanowire arrays by cryogenic reactive ion etching as a lithium-ion battery anode. Scientific Reports, 2021, 11, 19779.	3.3	36
23	Shallow and deep dry etching of silicon using ICP cryogenic reactive ion etching process. Microsystem Technologies, 2010, 16, 863-870.	2.0	34
24	Analysis of asymmetric resonance response of thermally excited silicon micro-cantilevers for mass-sensitive nanoparticle detection. Journal of Micromechanics and Microengineering, 2017, 27, 064001.	2.6	33
25	Towards fabrication of 3D isotopically modulated vertical silicon nanowires in selective areas by nanosphere lithography. Microelectronic Engineering, 2017, 179, 74-82.	2.4	32
26	Production of vertical nanowire resonators by cryogenic-ICPâ€DRIE. Microsystem Technologies, 2014, 20, 759-767.	2.0	31
27	Finite element modeling and experimental proof of NEMS-based silicon pillar resonators for nanoparticle mass sensing applications. Microsystem Technologies, 2014, 20, 571-584.	2.0	31
28	Anodic Dissolution during Electrochemical Carrierâ€Concentration Profiling of Silicon. Journal of the Electrochemical Society, 1992, 139, 552-557.	2.9	30
29	Longitudinal and transversal piezoresistive effect in hydrogenated amorphous carbon films. Thin Solid Films, 2007, 515, 8028-8033.	1.8	30
30	Evaluation of photoresist-based nanoparticle removal method for recycling silicon cantilever mass sensors. Sensors and Actuators A: Physical, 2013, 202, 90-99.	4.1	30
31	Wet Chemical Etching of Alignment Vâ€Grooves in (100) InP through Titanium or In _{0.53} Ga _{0.47} As Masks. Journal of the Electrochemical Society, 1994, 141, 1594-1599.	2.9	28
32	A low-frequency micromechanical resonant vibration sensor for wear monitoring. Sensors and Actuators A: Physical, 1997, 62, 616-620.	4.1	27
33	Piezoresistive gauge factor of hydrogenated amorphous carbon films. Journal of Micromechanics and Microengineering, 2006, 16, S75-S81.	2.6	27
34	Nanoindentation of crystalline silicon pillars fabricated by soft UV nanoimprint lithography and cryogenic deep reactive ion etching. Sensors and Actuators A: Physical, 2018, 283, 65-78.	4.1	27
35	Vertical silicon nanowire arrayâ€patterned microcantilever resonators for enhanced detection of cigarette smoke aerosols. Micro and Nano Letters, 2014, 9, 676-679.	1.3	26
36	Enhanced performance of pocket-sized nanoparticle exposure monitor for healthy indoor environment. Building and Environment, 2016, 95, 13-20.	6.9	25

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37	Piezoelectric MEMS Resonators for Cigarette Particle Detection. <i>Micromachines</i> , 2019, 10, 145.	2.9	25
38	The piezoresistive effect in diamond-like carbon films. <i>Journal of Micromechanics and Microengineering</i> , 2007, 17, S77-S82.	2.6	23
39	Nondestructive Evaluation of Diesel Spray Holes Using Piezoresistive Sensors. <i>IEEE Sensors Journal</i> , 2013, 13, 701-708.	4.7	22
40	Partially integrated cantilever-based airborne nanoparticle detector for continuous carbon aerosol mass concentration monitoring. <i>Journal of Sensors and Sensor Systems</i> , 2015, 4, 111-123.	0.9	22
41	Vertically Aligned n-Type Silicon Nanowire Array as a Free-Standing Anode for Lithium-Ion Batteries. <i>Nanomaterials</i> , 2021, 11, 3137.	4.1	21
42	Growth of InP Layers on Nanometer-Scale Patterned Si Substrates. <i>Crystal Growth and Design</i> , 2003, 3, 89-93.	3.0	20
43	Nanowire silicon as a material for thermoelectric energy conversion. <i>Microsystem Technologies</i> , 2012, 18, 857-862.	2.0	19
44	High-Temperature Performance of Stacked Silicon Nanowires for Thermoelectric Power Generation. <i>Journal of Electronic Materials</i> , 2013, 42, 2233-2238.	2.2	19
45	Real-Time Frequency Tracking of an Electro-Thermal Piezoresistive Cantilever Resonator with ZnO Nanorods for Chemical Sensing. <i>Chemosensors</i> , 2019, 7, 2.	3.6	19
46	Piezoresistive Microcantilever with SAM-Modified ZnO-Nanorods@Silicon-Nanopillars for Room-Temperature Parts-per-Billion NO ₂ Detection. <i>ACS Applied Nano Materials</i> , 2020, 3, 6609-6620.	5.0	19
47	In-Plane and Out-of-Plane MEMS Piezoresistive Cantilever Sensors for Nanoparticle Mass Detection. <i>Sensors</i> , 2020, 20, 618.	3.8	19
48	Force calibration of stylus instruments using silicon microcantilevers. <i>Sensors and Actuators A: Physical</i> , 2005, 123-124, 137-145.	4.1	18
49	Silicon Nanowire Resonators: Aerosol Nanoparticle Mass Sensing in the Workplace. <i>IEEE Nanotechnology Magazine</i> , 2013, 7, 18-23.	1.3	18
50	Piezoresistive Silicon Cantilever Covered by ZnO Nanorods for Humidity Sensing. <i>Procedia Engineering</i> , 2016, 168, 1114-1117.	1.2	18
51	A new maskless selective growth process for InP on (100) Si. <i>Journal of Applied Physics</i> , 1992, 72, 4366-4368.	2.5	17
52	Effect of III/V-Compound Epitaxy on Si Metal-Oxide-Semiconductor Circuits. <i>Japanese Journal of Applied Physics</i> , 1994, 33, 3628-3634.	1.5	17
53	Performance of InGaAs metal-semiconductor-metal photodetectors on Si. <i>IEEE Photonics Technology Letters</i> , 1996, 8, 670-672.	2.5	17
54	The effect of dislocations on the optical absorption of heteroepitaxial InP and GaAs on Si. <i>Journal of Applied Physics</i> , 1996, 79, 9273-9277.	2.5	17

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55	Characterization of surface damage in dry-etched InP. <i>Semiconductor Science and Technology</i> , 1997, 12, 755-759.	2.0	17
56	Thermal characterization of vertical silicon nanowires. <i>Journal of Materials Research</i> , 2011, 26, 1958-1962.	2.6	17
57	The distribution of charge concentration in InP/Si. <i>Journal of Applied Physics</i> , 1995, 78, 224-228.	2.5	16
58	Silicon cantilever sensor for micro-/nanoscale dimension and force metrology. <i>Microsystem Technologies</i> , 2008, 14, 441-451.	2.0	16
59	Transferable micromachined piezoresistive force sensor with integrated double-meander-spring system. <i>Journal of Sensors and Sensor Systems</i> , 2017, 6, 121-133.	0.9	16
60	Scattering mechanisms and defects in InP epitaxially grown on (001) Si substrates. <i>Journal of Applied Physics</i> , 1994, 76, 4705-4712.	2.5	15
61	Thermoelectric Coolers with Sintered Silver Interconnects. <i>Journal of Electronic Materials</i> , 2014, 43, 2397-2404.	2.2	15
62	Fabrication of ZnO Nanorods on MEMS Piezoresistive Silicon Microcantilevers for Environmental Monitoring. <i>Proceedings (mdpi)</i> , 2017, 1, .	0.2	15
63	GaN nanorods and LED structures grown on patterned Si and AlN/Si substrates by selective area growth. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2010, 7, 2224-2226.	0.8	14
64	The effect of dislocations on the transport properties of III/V compound semiconductors on Si. <i>Journal of Applied Physics</i> , 1995, 78, 6141-6146.	2.5	13
65	High-quality In _{0.53} Ga _{0.47} As on exactly (001)-oriented Si grown by metal-organic vapour-phase epitaxy. <i>Journal of Crystal Growth</i> , 1997, 172, 44-52.	1.5	13
66	A micromachined vibration sensor based on the control of power transmitted between optical fibres. <i>Sensors and Actuators A: Physical</i> , 1998, 65, 23-29.	4.1	13
67	The effect of threading dislocations on optical absorption and electron scattering in strongly mismatched heteroepitaxial III/V compound semiconductors on silicon. <i>Journal of Physics Condensed Matter</i> , 2002, 14, 13195-13201.	1.8	13
68	Automatic counting of etch Pits in InP. <i>Journal of Electronic Materials</i> , 1992, 21, 887-892.	2.2	12
69	Dopant activation energy and hole effective mass in heavily Zn-Doped InP. <i>Journal of Electronic Materials</i> , 1994, 23, 935-941.	2.2	12
70	Micromachining of silicon carbide on silicon fabricated by low-pressure chemical vapour deposition. <i>Journal of Micromechanics and Microengineering</i> , 2002, 12, 380-384.	2.6	12
71	Long Slender Piezo-Resistive Silicon Microprobes for Fast Measurements of Roughness and Mechanical Properties inside Micro-Holes with Diameters below 100 Åm. <i>Sensors</i> , 2019, 19, 1410.	3.8	12
72	GaN and LED structures grown on pre-patterned silicon pillar arrays. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2010, 7, 84-87.	0.8	11

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73	Fabrication, packaging, and characterization of p-SOI Wheatstone bridges for harsh environments. <i>Microsystem Technologies</i> , 2012, 18, 869-878.	2.0	11
74	High-speed microprobe for roughness measurements in high-aspect-ratio microstructures. <i>Measurement Science and Technology</i> , 2017, 28, 034009.	2.6	11
75	Area-Selective Growth of Aligned ZnO Nanorod Arrays for MEMS Device Applications. <i>Proceedings (mdpi)</i> , 2018, 2, .	0.2	11
76	Traceable Nanomechanical Metrology of GaN Micropillar Array. <i>Advanced Engineering Materials</i> , 2018, 20, 1800353.	3.5	11
77	Contact resonance spectroscopy for on-the-machine manufactory monitoring. <i>Sensors and Actuators A: Physical</i> , 2018, 279, 501-508.	4.1	11
78	Cantilever-Droplet-Based Sensing of Magnetic Particle Concentrations in Liquids. <i>Sensors</i> , 2019, 19, 4758.	3.8	11
79	Quantitative scanning spreading resistance microscopy on n-type dopant diffusion profiles in germanium and the origin of dopant deactivation. <i>Journal of Applied Physics</i> , 2019, 125, .	2.5	11
80	Strategy toward Miniaturized, Self-out-Readable Resonant Cantilever and Integrated Electrostatic Microchannel Separator for Highly Sensitive Airborne Nanoparticle Detection. <i>Sensors</i> , 2019, 19, 901.	3.8	11
81	In-Line Measurement of the Surface Texture of Rolls Using Long Slender Piezoresistive Microprobes. <i>Sensors</i> , 2021, 21, 5955.	3.8	11
82	Fractures properties of InP microcantilevers by hetero-micromachining. <i>Sensors and Actuators A: Physical</i> , 1999, 76, 395-402.	4.1	10
83	Gallium nitride heterostructures on 3D structured silicon. <i>Nanotechnology</i> , 2008, 19, 405301.	2.6	10
84	Measurements of thermoelectric properties of silicon pillars. <i>Sensors and Actuators A: Physical</i> , 2011, 171, 48-48.	4.1	10
85	Size-selective electrostatic sampling and removal of nanoparticles on silicon cantilever sensors for air-quality monitoring. , 2017, , .		10
86	Determination of exposure to engineered carbon nanoparticles using a self-sensing piezoresistive silicon cantilever sensor. <i>Microsystem Technologies</i> , 2012, 18, 905-915.	2.0	9
87	Improvement of frequency responses of an in-plane electro-thermal cantilever sensor for real-time measurement. <i>Journal of Micromechanics and Microengineering</i> , 2019, 29, 124006.	2.6	9
88	Fabrication of a microcantilever-based aerosol detector with integrated electrostatic on-chip ultrafine particle separation and collection. <i>Journal of Micromechanics and Microengineering</i> , 2020, 30, 014001.	2.6	9
89	Microelectromechanical vibration sensor with optical interconnects. <i>Journal of Microelectromechanical Systems</i> , 1998, 7, 56-61.	2.5	8
90	Temperature dependence of residual stress in epitaxial GaAs/Si(100) films determined from photorefectance spectroscopy data. <i>Semiconductors</i> , 2000, 34, 73-80.	0.5	8

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91	Three-dimensionally structured silicon as a substrate for the MOVPE growth of GaN nanoLEDs. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2009, 206, 1194-1198.	1.8	8
92	MEMS cantilever sensor for non-destructive metrology within high-aspect-ratio micro holes. <i>Microsystem Technologies</i> , 2010, 16, 1259-1268.	2.0	8
93	Die-attach for high-temperature applications using fineplacer-pressure-sintering (FPS). , 2010, , .		8
94	Double-meander spring silicon piezoresistive sensors as microforce calibration standards. <i>Optical Engineering</i> , 2016, 55, 091409.	1.0	8
95	Ultrafine Aerosol Particle Sizer Based on Piezoresistive Microcantilever Resonators with Integrated Air-Flow Channel. <i>Sensors</i> , 2021, 21, 3731.	3.8	8
96	Phase optimization of thermally actuated piezoresistive resonant MEMS cantilever sensors. <i>Journal of Sensors and Sensor Systems</i> , 2019, 8, 37-48.	0.9	8
97	Micromachined resonator for cavitation sensing. <i>Sensors and Actuators A: Physical</i> , 1999, 76, 266-272.	4.1	7
98	Investigation of Thermoelectric Parameters of Bi ₂ Te ₃ : TEGs Assembled using Pressure-Assisted Silver Powder Sintering-Based Joining Technology. <i>Journal of Electronic Materials</i> , 2015, 44, 2055-2060.	2.2	7
99	Smart sensors and calibration standards for high precision metrology. <i>Proceedings of SPIE</i> , 2015, , .	0.8	7
100	Silicon Microcantilevers with ZnO Nanorods/Chitosan-SAMs Hybrids on Its Back Surface for Humidity Sensing. <i>Proceedings (mdpi)</i> , 2018, 2, .	0.2	7
101	Self-actuating and self-sensing ZNO nanorods/chitosan coated piezoresistive silicon microcantilever for humidity sensing. , 2018, , .		7
102	Performance of an Electrothermal MEMS Cantilever Resonator with Fano-Resonance Annoyance under Cigarette Smoke Exposure. <i>Sensors</i> , 2021, 21, 4088.	3.8	7
103	Hetero-micromachining of epitaxial III/V compound semiconductors. <i>Sensors and Actuators A: Physical</i> , 2000, 85, 324-329.	4.1	6
104	Mechanical spectroscopy of thin polystyrene films. <i>Polymer</i> , 2008, 49, 2115-2118.	3.8	6
105	Packaging of MEMS and MOEMS for harsh environments. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2012, 11, 021202-1.	0.9	6
106	Gravimetric humidity sensor based on ZnO nanorods covered piezoresistive Si microcantilever. , 2017, , .		6
107	Characterization of diesel injectors using piezoresistive sensors. , 2010, , .		5
108	Surface finish improvement of deep micro bores monitored using an active MEMS cantilever probe. , 2010, , .		5

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109	Femtogram Mass Measurement of Airborne Engineered Nanoparticles using Silicon Nanopillar Resonators. <i>Procedia Engineering</i> , 2012, 47, 289-292.	1.2	5
110	Cantilever Sensors. <i>Sensors</i> , 2019, 19, 2043.	3.8	5
111	Defect distribution in boron doped silicon nanostructures characterized by means of scanning spreading resistance microscopy. <i>Journal of Applied Physics</i> , 2020, 127, .	2.5	5
112	A Theoretical Model of InP Mass Transport. <i>Japanese Journal of Applied Physics</i> , 1993, 32, 234-238.	1.5	4
113	A procedure for temperatureâ€dependent, differential van der Pauw measurements. <i>Review of Scientific Instruments</i> , 1995, 66, 4271-4276.	1.3	4
114	Slender Tactile Sensor for High-Aspect-Ratio Micro Metrology. , 2007, , .		4
115	Neue taktile Sensoren f¼r die Mikro- und NanotechnikNew Tactile Sensors for Micro- and Nanotechnology. <i>TM Technisches Messen</i> , 2009, 76, 323-331.	0.7	4
116	MEMS-based silicon cantilevers with integrated electrothermal heaters for airborne ultrafine particle sensing. <i>Proceedings of SPIE</i> , 2013, , .	0.8	4
117	Nanomechanical Characterization of Vertical Nanopillars Using an MEMS-SPM Nano-Bending Testing Platform. <i>Sensors</i> , 2019, 19, 4529.	3.8	4
118	Sampling and Mass Detection of a Countable Number of Microparticles Using on-Cantilever Imprinting. <i>Sensors</i> , 2020, 20, 2508.	3.8	4
119	Investigating the Trackability of Silicon Microprobes in High-Speed Surface Measurements. <i>Sensors</i> , 2021, 21, 1557.	3.8	4
120	Anisotropy and Lateral Homogeneity of InP-Mass Transport. <i>Japanese Journal of Applied Physics</i> , 1992, 31, L1153-L1156.	1.5	3
121	Compliant Tactile Sensors for High-Aspect-Ratio Form Metrology. , 0, , .		3
122	Design and fabrication of piezoresistive p-SOI Wheatstone bridges for high-temperature applications. , 2011, , .		3
123	Microtactile Cantilever Resonators for Characterizing Surface Deposits. <i>Procedia Engineering</i> , 2015, 120, 861-864.	1.2	3
124	Electrothermal piezoresistive cantilever resonators for personal measurements of nanoparticles in workplace exposure. <i>Proceedings of SPIE</i> , 2015, , .	0.8	3
125	Asymmetric resonance frequency analysis of in-plane electrothermal silicon cantilevers for nanoparticle sensors. <i>Journal of Physics: Conference Series</i> , 2016, 757, 012006.	0.4	3
126	Nanomechanical Traceable Metrology of Vertically Aligned Silicon and Germanium Nanowires by Nanoindentation. <i>Proceedings (mdpi)</i> , 2017, 1, 375.	0.2	3

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127	UV-LED Photo-Activated Room Temperature NO ₂ Sensors Based on Nanostructured ZnO/AlN Thin Films. Proceedings (mdpi), 2019, 2, .	0.2	3
128	Piezoresistive Microcantilevers 3D-Patterned Using Zno-Nanorods@Silicon-Nanopillars for Room-Temperature Ethanol Detection. , 2019, , .		3
129	Thermoelectric Generators Fabricated from Large-Scale-Produced Zr-/Hf-Based Half-Heusler Compounds Using Ag Sinter Bonding. Journal of Electronic Materials, 2019, 48, 5363-5374.	2.2	3
130	MEMS-Based Cantilever Sensor for Simultaneous Measurement of Mass and Magnetic Moment of Magnetic Particles. Chemosensors, 2021, 9, 207.	3.6	3
131	Condition monitoring with axle box bearings using resonant microelectromechanical sensors. Journal of Micromechanics and Microengineering, 2002, 12, 479-485.	2.6	2
132	Development of silicon microforce sensors integrated with double meander springs for standard hardness test instruments. , 2015, , .		2
133	Fabrication of wear-resistant silicon microprobe tips for high-speed surface roughness scanning devices. Proceedings of SPIE, 2015, , .	0.8	2
134	Optimizing a Cantilever Measurement System towards High Speed, Nonreactive Contact-Resonance-Profilometry. Proceedings (mdpi), 2018, 2, 889.	0.2	2
135	Fabrication and characterization of single-pair thermoelectric generators of bismuth telluride using silver-sintering technology. Materials Today: Proceedings, 2018, 5, 10401-10407.	1.8	2
136	ZNO Nanostructures Functionalized Piezoresistive Silicon Microcantilever Platform for Portable Gas Sensing. , 2019, , .		2
137	Ultra Low Power Mass-Producible Gas Sensor Based on Efficient Self-Heated GaN Nanorods. , 2019, , .		2
138	Silicon Nanopillars with ZNO Nanorods by Nanosphere Lithography on a Piezoresistive Microcantilever. , 2019, , .		2
139	Micromachined Silicon Cantilever Resonator-Based Humidity Sensors for Multifunctional Applications. , 2021, , .		2
140	Customized piezoresistive microprobes for combined imaging of topography and mechanical properties. Measurement: Sensors, 2021, 15, 100042.	1.7	2
141	Dimensional-Nanopatterned Piezoresistive Silicon Microcantilever for Environmental Sensing. , 2022, , 19-47.		2
142	Using a Tip Characterizer to Investigate Microprobe Silicon Tip Geometry Variation in Roughness Measurements. Sensors, 2022, 22, 1298.	3.8	2
143	Silicon cantilever sensor for micro-/nanoscale dimension and force metrology. , 2007, , .		1
144	Sinter-attach of high-temperature sensors for deep-drilling monitoring. , 2012, , .		1

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145	Effect of Photoresist Coating on the Reusable Resonant Cantilever Sensors for Assessing Exposure to Airborne Nanoparticles. <i>Procedia Engineering</i> , 2012, 47, 302-305.	1.2	1
146	Simulation and characterization of silicon nanopillar-based nanoparticle sensors. , 2013, , .		1
147	Direct-reading Resonant Silicon Cantilever for Probing of Surface Deposits. <i>Procedia Engineering</i> , 2016, 168, 658-661.	1.2	1
148	Large area contact resonance spectroscopy mapping system for on-the-machine measurements. , 2018, , .		1
149	Indentation modulus and hardness investigation of crystalline silicon surfaces treated by inductively coupled plasma reactive ion etching. <i>Journal of Physics: Conference Series</i> , 2019, 1319, 012008.	0.4	1
150	Fabrication of SiO ₂ microcantilever arrays for mechanical loss measurements. <i>Materials Research Express</i> , 2019, 6, 045206.	1.6	1
151	Influence of eccentric nanoindentation on top surface of silicon micropillar arrays. <i>Journal of Physics: Conference Series</i> , 2021, 1837, 012008.	0.4	1
152	Asymmetric resonance response analysis of a thermally excited silicon microcantilever for mass-sensitive nanoparticle detection. <i>Proceedings of SPIE</i> , 2017, , .	0.8	1
153	Calibrating a high-speed contact-resonance profilometer. <i>Journal of Sensors and Sensor Systems</i> , 2020, 9, 179-187.	0.9	1
154	Retarded boron and phosphorus diffusion in silicon nanopillars due to stress induced vacancy injection. <i>Journal of Applied Physics</i> , 2022, 131, 075702.	2.5	1
155	Kontur-, Rauheits- und Kraftmesstechnik mit Silizium-Cantileversonden (Shape, Roughness and Force) Tj ETQq1 1 0,784314 rgBT /Overlo	0.7	0
156	Silicon nanowire resonators for aerosol nanoparticle mass sensing. , 2013, , .		0
157	A closed-loop system for frequency tracking of piezoresistive cantilever sensors. , 2013, , .		0
158	Fabrication of vertical nanowire resonators for aerosol exposure assessment. <i>Proceedings of SPIE</i> , 2013, , .	0.8	0
159	In-plane-excited silicon nanowire arrays-patterned cantilever sensors for enhanced airborne particulate matter exposure detection. , 2014, , .		0
160	Large-area fabrication of silicon nanostructures by templated nanoparticle arrays. , 2017, , .		0
161	Design of Miniaturized, Self-Out-Readable Cantilever Resonator for Highly Sensitive Airborne Nanoparticle Detection. <i>Proceedings (mdpi)</i> , 2018, 2, .	0.2	0
162	Nanofabrication of SOI-Based Photonic Waveguide Resonators for Gravimetric Molecule Detection. <i>Proceedings (mdpi)</i> , 2018, 2, 1055.	0.2	0

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163	Efficient Self-Heating in Gallium Nitride Nanopillars for Ultra-Low-Power Mass-Productible Gas Sensors. , 2019, , .		0
164	Enhancement of unsteady frequency responses of electro-thermal resonance MEMS cantilever sensors. Journal of Physics: Conference Series, 2021, 1837, 012003.	0.4	0